



Attorney Docket No. 0756-7244

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Koichiro TANAKA et al.

Serial No. 10/749,505

Filed: January 2, 2004

For: LASER IRRADIATION METHOD,
METHOD FOR MANUFACTURING
SEMICONDUCTOR DEVICE, AND
LASER IRRADIATION SYSTEM

) Group Art Unit: 2822

) Examiner: Mary A. Wilczewski

) CERTIFICATE OF MAILING

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AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated February 12, 2007, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 15 of this paper.